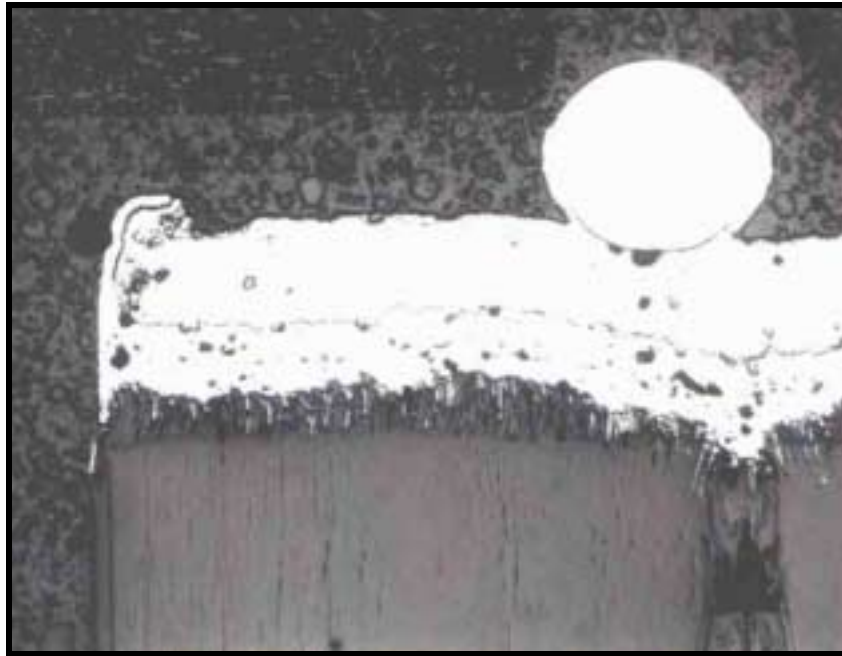


# MetPrep Preparation Procedure – No 199



## Electronic Component Condenser

	Surface	Abrasive	Pressure		Speed – Dir	Time
			Psi	N		
Primary Grinding Stage	Paper	P240g SiC	5	25	150 – Comp	Until Planar

	Surface	Abrasive	Pressure		Speed – Dir	Time
			Psi	N		
Additional Grinding Stages	Planocloth H	9 µm (OB) PCD Diamond	5	25	250 – Comp	5 mins
	Durasilk	3 µm (OB) PCD Diamond	5	25	250 – Comp	4 mins

	Surface	Abrasive	Pressure		Speed – Dir	Time
			Psi	N		
Polishing Stage	Trounoire	0.25 µm (OB) PCD Diamond	3	15	100 – Comp	3 mins